

DOCKET NO: 247903US90CONT



IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :  
TETSUO TANIGUCHI : EXAMINER: NGUYEN, H.  
SERIAL NO: 10/773,293 :  
FILED: FEBRUARY 9, 2004 : GROUP ART UNIT: 2851  
FOR: EXPOSURE METHOD AND :  
LITHOGRAPHY SYSTEM, EXPOSURE  
APPARATUS AND METHOD OF  
MAKING THE APPARATUS, AND  
METHOD OF MANUFACTURING  
DEVICE

**PRELIMINARY AMENDMENT**  
**AND**  
**RESPONSE TO RESTRICTION REQUIREMENT**

COMMISSIONER FOR PATENTS  
ALEXANDRIA, VIRGINIA 22313

SIR:

Responsive to the Restriction Requirement stated in the Office Action dated October 8, 2004 and prior to an examination on the merits, please amend the above-identified patent application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks** begin on page 9 of this paper.